Form PTO 1449 (Modified)		U.S. DEPARTMENT O		ATTY DOCKET NO.		SERIAL NO.	
(Modified)		TATE TO THE PART OF THE		271672US2PCT		10/533,810	
				PPLICANT			
LIST OF REFERENCES CITED BY APPLICANT Shigeki SAKAI							
				FILING DATE		GROUP	
				September 8, 2005		1792	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
,	AA						_
	AB	,					
	AC						
	AD						
	AE					 	
	AF						
	AG		·			i i	·
	AH						
	Al						···
	AJ						· · · · · · · · · · · · · · · · · · ·
	AK						
	AL				1		·
	AM						• • • • • • • • • • • • • • • • • • • •
	AN						
	AN				L		
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY		TRANSLATION YES NO	
-	AO	JP 62-180063	08/07/1987	Japan (With English Abstract)	•		Х
	AP	JP 02-163374	06/22/1990	Japan (With English Abstract)			Х
	AQ	JP 60-162774	08/24/1985	Japan (With English Abstract)			Х
	AR				· -		
	AS						
	AT						
	AU						
	AV						<u> </u>
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
Deppisch, G. "Schichtdickengleichmäßigkeit von aufgestäubten Schichten - Vergleich zwischen Berechnungen und							
	AW	praktischen Ergebnissen" [Layer Thickness Uniformity of Spray Coated Films - Comparison Between Calculations and Practical Results]. Vakuum-Technik, Vol. 30, Issue 4, 1981. pp. 106 - 114.					
	AX	Greer, J.A. and Tabat, M.D. "Large-area pulsed laser deposition: Techniques and applications". Journal of Vacuum Sci. Technology, A 13 (3), May/June 1995. American Vacuum Society, 1995. pp. 1175-1181.					
	AY	Dietsch, R., et al. "Large area PLD of nanometer-multilayers". Applied Surface Science, 197-198, 2002. pp. 169-174.					
	AZ				Addi	itional Refe	erences sheet(s) attached
Examiner /Kelly Stouffer/					Date Considered 07/28/2009		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							